

Special Issue

Piezoelectric Thin Film MEMS

Message from the Guest Editor

Piezoelectric MEMS are successfully commercialized as ink-jet heads and actuators. Moreover, they have attracted more and more attention for the application to optical scanners, ultrasonic sensors, speakers, and so on. In this Special Issue, *Micromachines* invites original research papers related to piezoelectric MEMS, including piezoelectric thin films, fabrication processes, evaluations, and devices.

Guest Editor

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Deadline for manuscript submissions

closed (30 November 2020)



Micromachines

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Impact Factor 3.0
CiteScore 6.0
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mdpi.com/si/35476

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Message from the Editor-in-Chief

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Editor-in-Chief

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